

Cooke Anneal Oven

Operating Procedures [LINK](#)



Process Description:

The use of various polyimide films is widespread in MEMS fabrication. The curing process of these polyimide films requires a controlled vacuum annealer.

Equipment Description:

The Cooke Vacuum Annealer is a water-cooled system with nitrogen as the process gas. The maximum programmable process temperature is 300°C. The vacuum is produced by mechanical pump and will reach a base pressure of 100mTorr.

<i>Materials Allowed</i>	<i>Materials Not Allowed</i>
Glass	Metals
Polyimide	Photoresists
Silicon	
SiO ₂	
Si ₃ N ₄	